

11-02-1999

MRD 10/29/99



To the Honorable Commissioner of

101186908

ached original documents or copy thereof.

<p>1. Name of conveying party(ies): Lawrence S. Mok</p> <p>Additional names of conveying party(ies) attached? <input type="checkbox"/> yes <input checked="" type="checkbox"/> no</p> <p>3. Nature of Conveyance <input checked="" type="checkbox"/> Assignment <input type="checkbox"/> Merger <input type="checkbox"/> Security Agreement <input type="checkbox"/> Change of Name <input type="checkbox"/> Other _____</p> <p>Execution Date: August 10, 1999</p>	<p>2. Name and address of receiving party(ies): Name: <u>International Business Machines Corporation</u> Internal Address: _____ _____ _____ Street Address: <u>New Orchard Road</u> City <u>Armonk</u> State <u>New York</u> Zip <u>10504</u></p> <p>Additional name(s) & address(es) attached? <input type="checkbox"/> yes <input checked="" type="checkbox"/> no</p>
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4. Application number(s) or patent number(s):
Title: IMPROVED METHOD AND APPARATUS FOR CHEMICAL MECHANICAL PLANARIZATIONS (CMP) OF A SEMICONDUCTOR WAFER
If this document is being filed together with a new application, the execution date of the application is _____

A. Patent Application No(s). 09/036,478 filed on March 6, 1998 B. Patent No(s). _____

Additional numbers attached? Yes No

<p>5. Name and address of party to whom correspondence concerning document should be mailed: Kevin A. Reif, Esq. Whitham, Curtis & Whitham Reston International Center 11800 Sunrise Valley Drive, Suite 900 Reston, Virginia 20191</p>	<p>6. Total number of applications and patents involved: <u>1</u></p> <p>7. Total fee (37 CFR 3.41): <u>\$ 40.00</u></p> <p><input checked="" type="checkbox"/> Enclosed <input checked="" type="checkbox"/> Authorized to be charged to deposit account <input type="checkbox"/> Total fee due <input checked="" type="checkbox"/> Any deficiencies in the enclosed fees</p> <p>8. Deposit account number: 23-1951</p>
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DO NOT USE THIS SPACE

9. Statement and signature
To the best of my knowledge and belief, the foregoing information is true and correct and any attached copy is a true copy of the original document.

Kevin A. Reif 10/29/99
Registration 36,381 Signature Date
Tel.: (703) 391-2510 Total number of pages including cover sheet, attachments, and document: 2

11/01/1999 MTHA11 00000215 09036478
01 FC:581 40.00 DP

ASSIGNMENT

Whereas, I

Inventor
and city

(1) Lawrence S. Mok
State of New York

City of Brewster, New York
County of Putnam

have invented certain improvements in

TITLE

IMPROVED METHOD AND APPARATUS FOR CHEMICAL MECHANICAL PLANARIZATIONS
(CMP) OF A SEMICONDUCTOR WAFER

and have executed, respectively, a United States patent application therefor on

DATE THAT
INVENTOR
SIGNED THE
DECLARATION

(1) August 10, 1999.

Whereas, INTERNATIONAL BUSINESS MACHINES CORPORATION, a corporation of New York, having a place of business at Armonk, New York 10504, (hereinafter called IBM), desires to acquire the entire right, title and interest in the said application and invention, and to any United States and foreign patents to be obtained therefor;

Now therefore, for a valuable consideration, receipt whereof is hereby acknowledged, we the above named hereby sell, assign, and transfer to IBM, its successors and assigns, the entire right, title and interest in the said application and invention therein disclosed for the United States and foreign countries, and all rights of priority resulting from the filing of said United States application, and we request the Commissioner of Patents to issue any Letters Patent granted upon the invention set forth in said application to IBM, its successors and assigns; and we hereby agree that IBM may apply for foreign Letters Patent on said invention and we will execute all papers necessary in connection with the United States and foreign applications when called upon to do so by IBM.

(1) Signed and sealed

CITY
DATE

at Yorktown Heights, N.Y.

on 8/10/1999 1999

Lawrence
FIRST NAME

S.
MIDDLE INITIAL

Mok
LAST NAME

SIGNATURE
INVENTOR

IN THE U.S. PATENT AND TRADEMARK OFFICE

In re patent application of

Lawrence S. Mok et al.

Serial No.: 09/036,478



Group Art Unit: Unknown

Filed: March 6, 1998

Examiner: Unknown

For: IMPROVED METHOD AND APPARATUS FOR CHEMICAL MECHANICAL
PLANARIZATIONS (CMP) OF A SEMICONDUCTOR WAFER

Assistant Commissioner for Patents
Washington, D.C. 20231

SUBMISSION OF ASSIGNMENT

Sir:

Kindly record and return to the undersigned the attached assignment from Lawrence S. Mok to INTERNATIONAL BUSINESS MACHINES CORPORATION, for the above-identified patent application. Enclosed is a check in the amount of \$40.00 to cover the recordation fee. Please charge any deficiencies in payments and credit any overpayments to Attorney's deposit account no. 23-1951 (Whitham, Curtis & Whitham).

Respectfully submitted,

A handwritten signature in cursive script, appearing to read "Kevin A. Reif".

Kevin A. Reif
Reg. No.: 36,381

Whitham, Curtis & Whitham
Reston International Center
11800 Sunrise Valley Drive - Suite 900
Reston, Virginia 20191
(703) 391-2510